

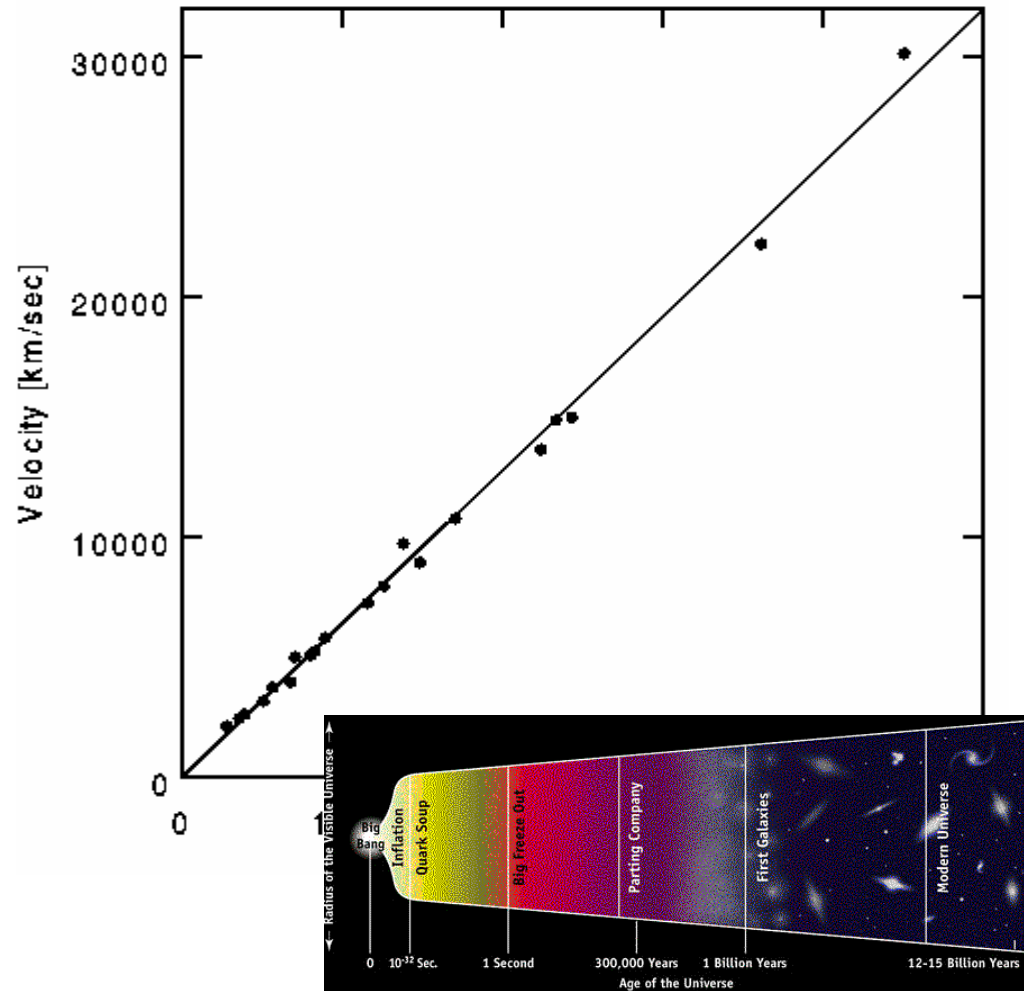
# Future Trends in Microelectronics – Impact on Detector Readout

Paul O'Connor

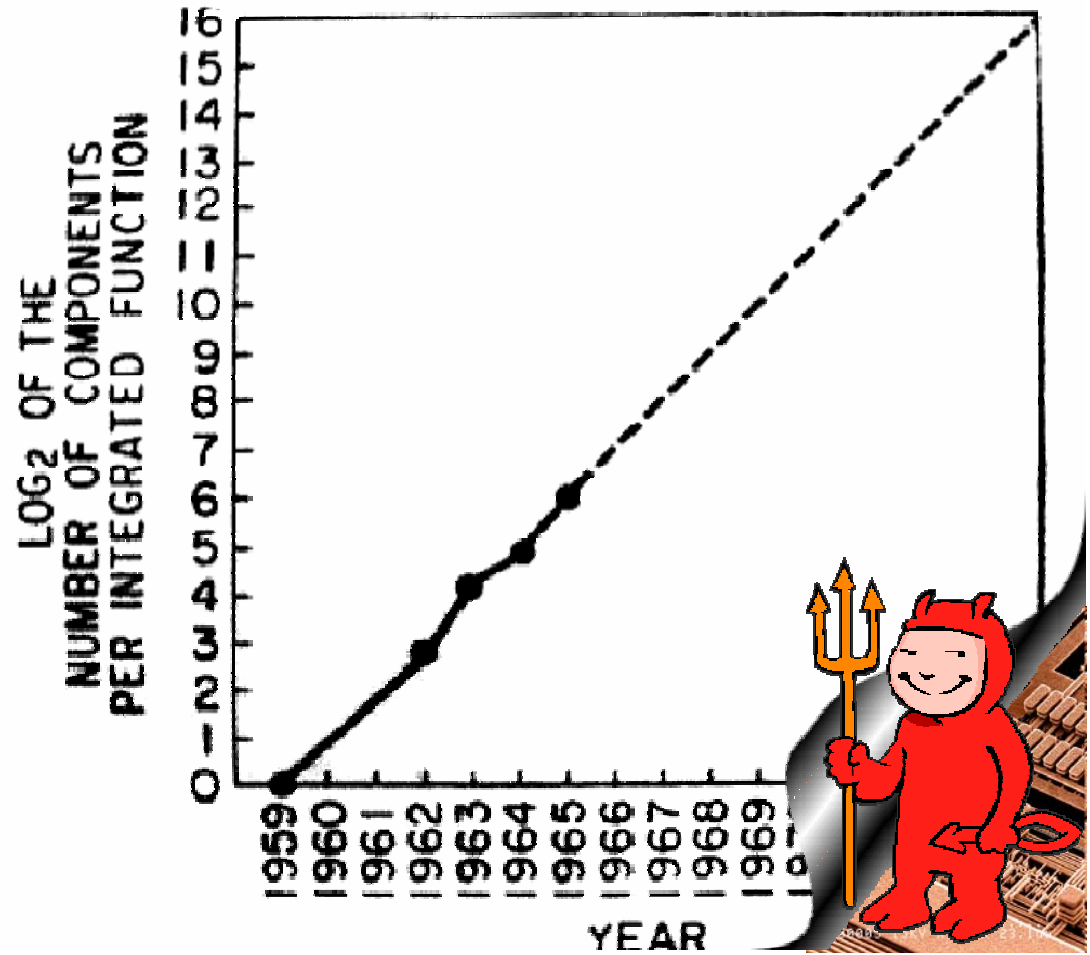
# Outline

- CMOS Technology Scaling
- Analog Circuits
- Radiation Effects
- Cost

# Edwin Hubble

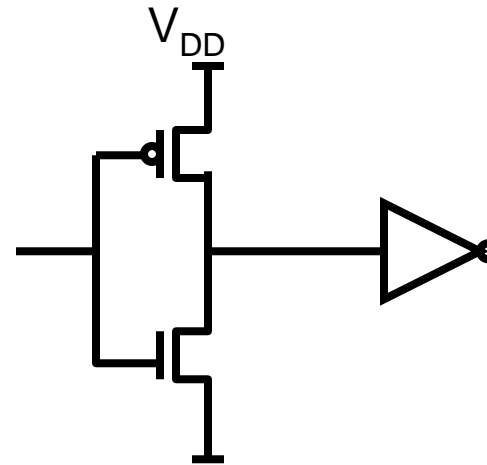


# Gordon Moore

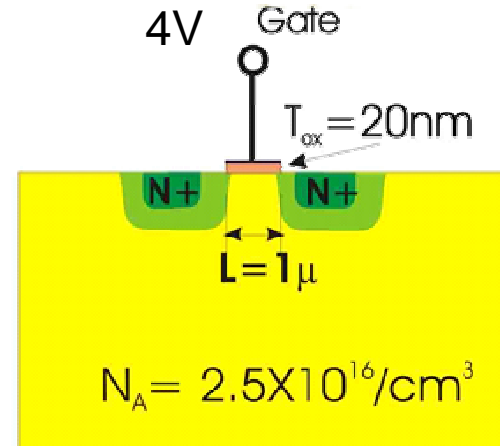
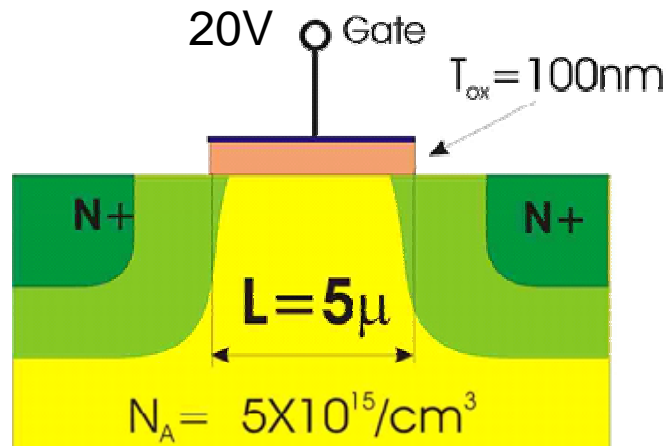


# CMOS Logic Element

- Pair of nearly-ideal switches in series
- Complementary polarity  $\Rightarrow$  common control voltage
- input impedance  $\sim \infty$
- $V_{DD}$ -tolerant
- Zero static power



# MOSFET Scaling



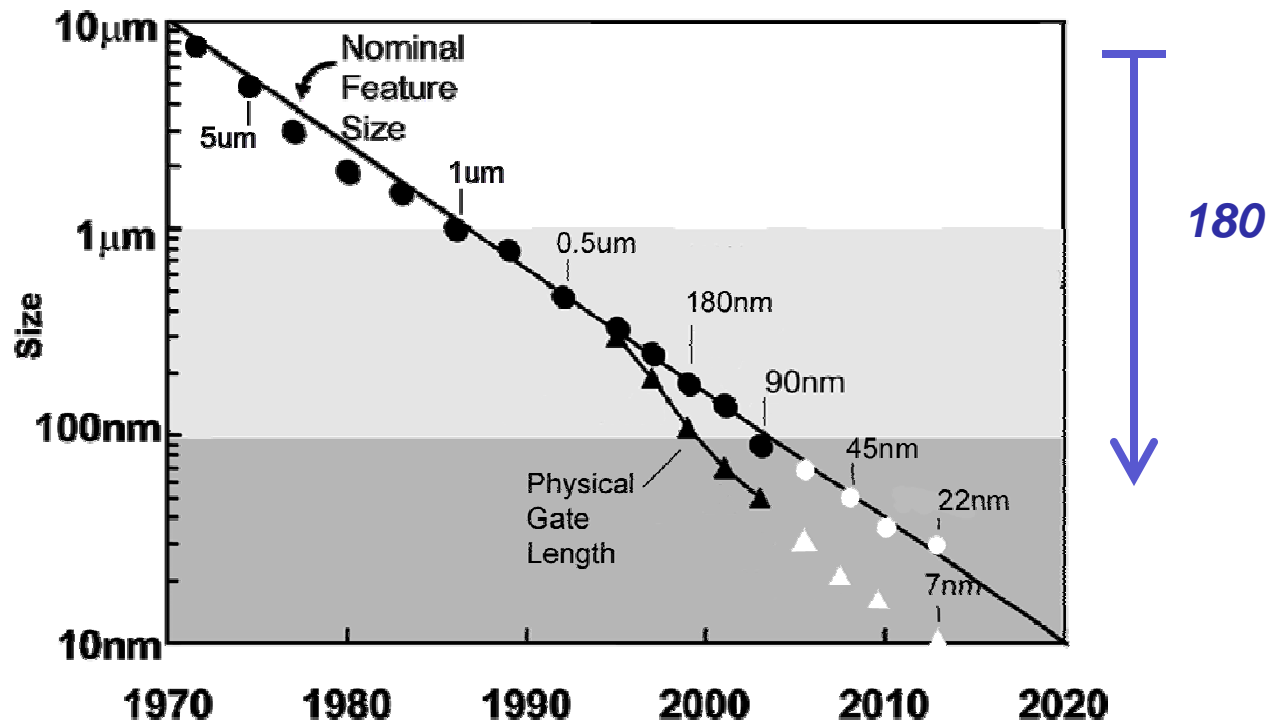
- Voltages, dimensions reduced by  $\alpha$
- Results:

$\vec{E} =$		const.
Conductance	$I/V$	const.
Capacitance		$\frac{1}{\alpha}$
Speed	$I/CV$	$\alpha$

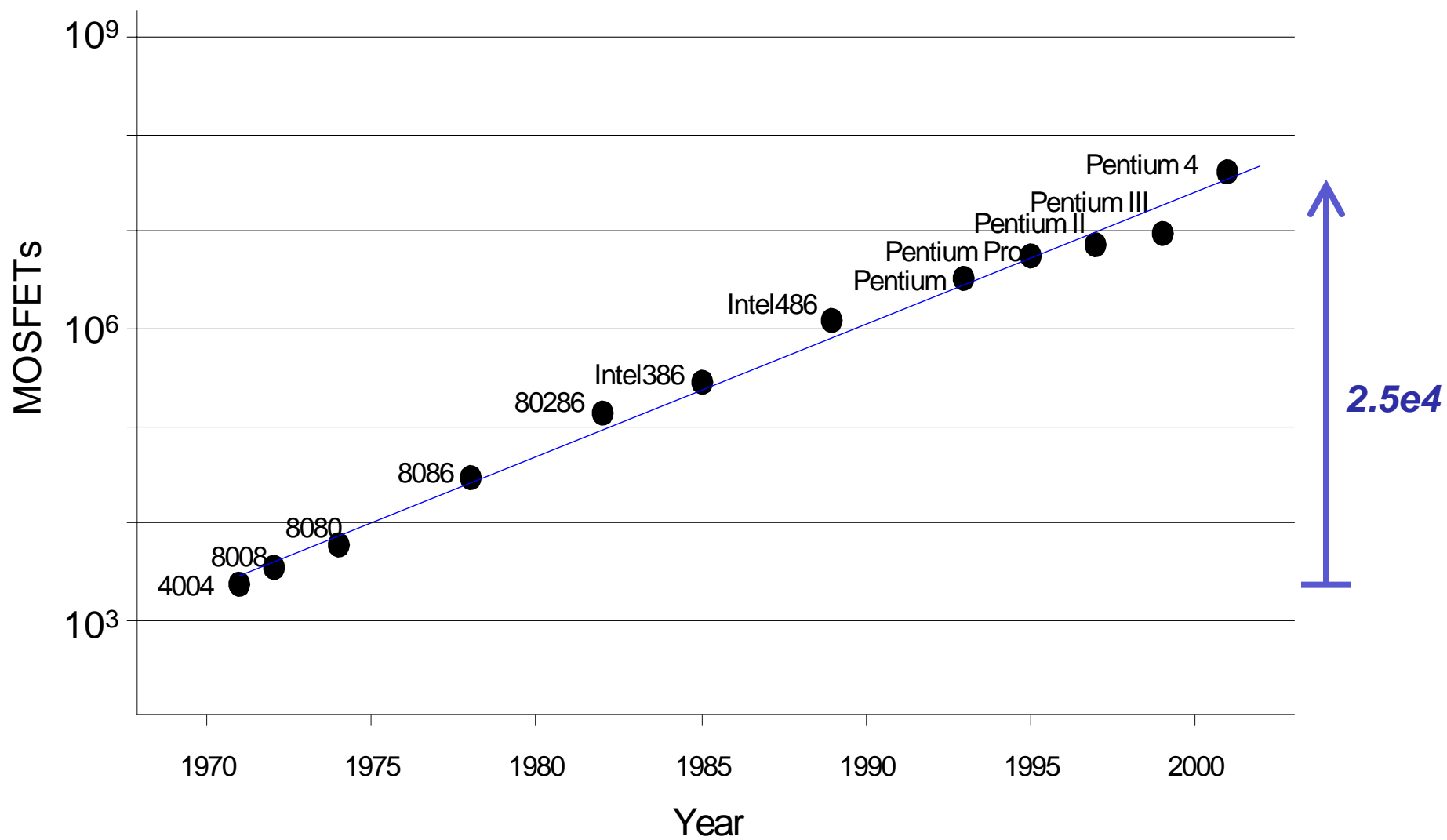
Switching energy	$CV^2$	$\frac{1}{\alpha^3}$
Power/gate	$CV^2f$	$\frac{1}{\alpha^2}$
Density		$\alpha^2$
Power density		const.

# Industry Scaling Roadmap

- New generation every  $\sim 2$  years with  $\alpha = \sqrt{2}$
- $L_g$  (1970)  $8 \mu\text{m}$  (2007)  $18 \text{ nm}$

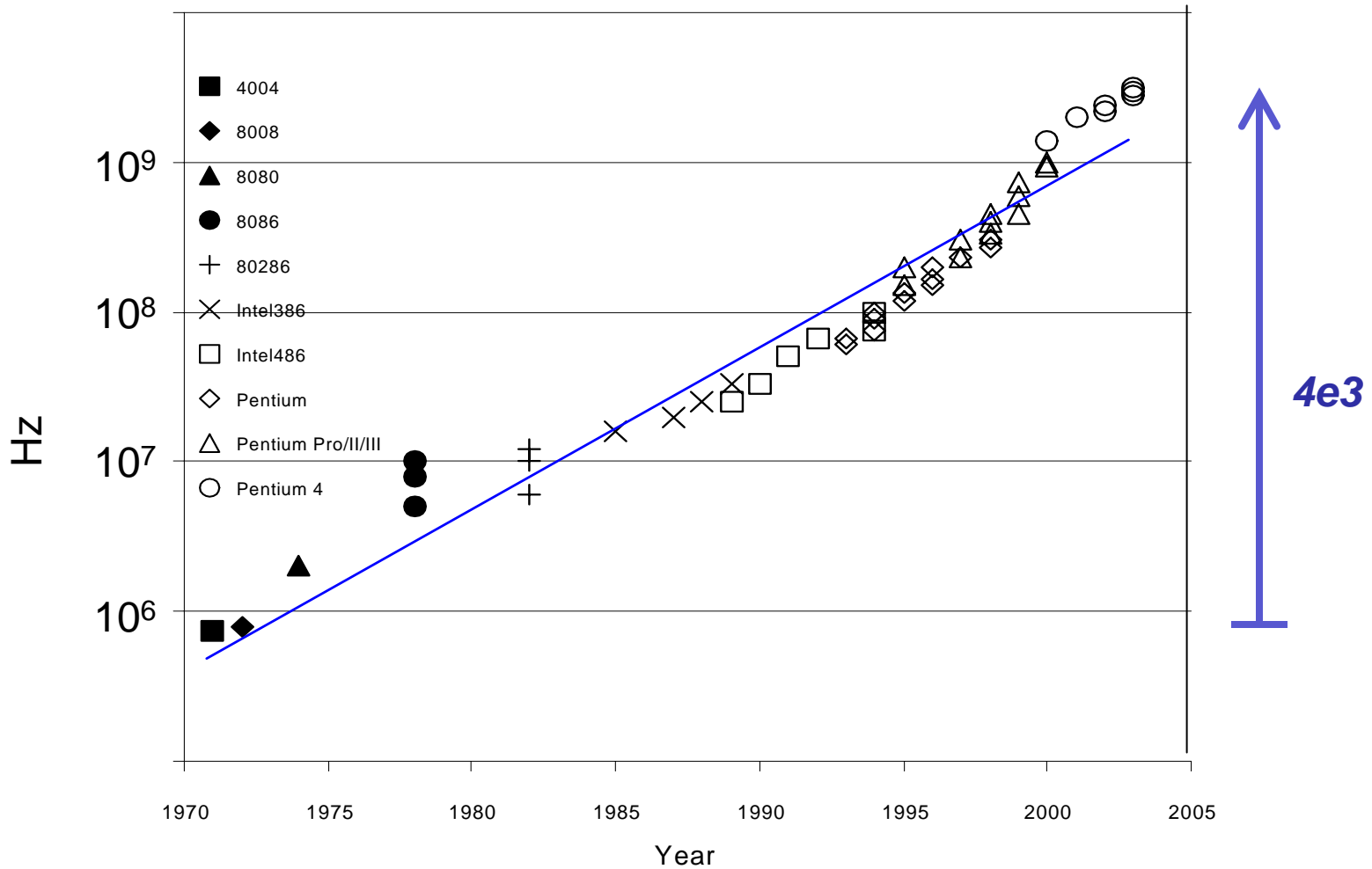


# Transistor Count

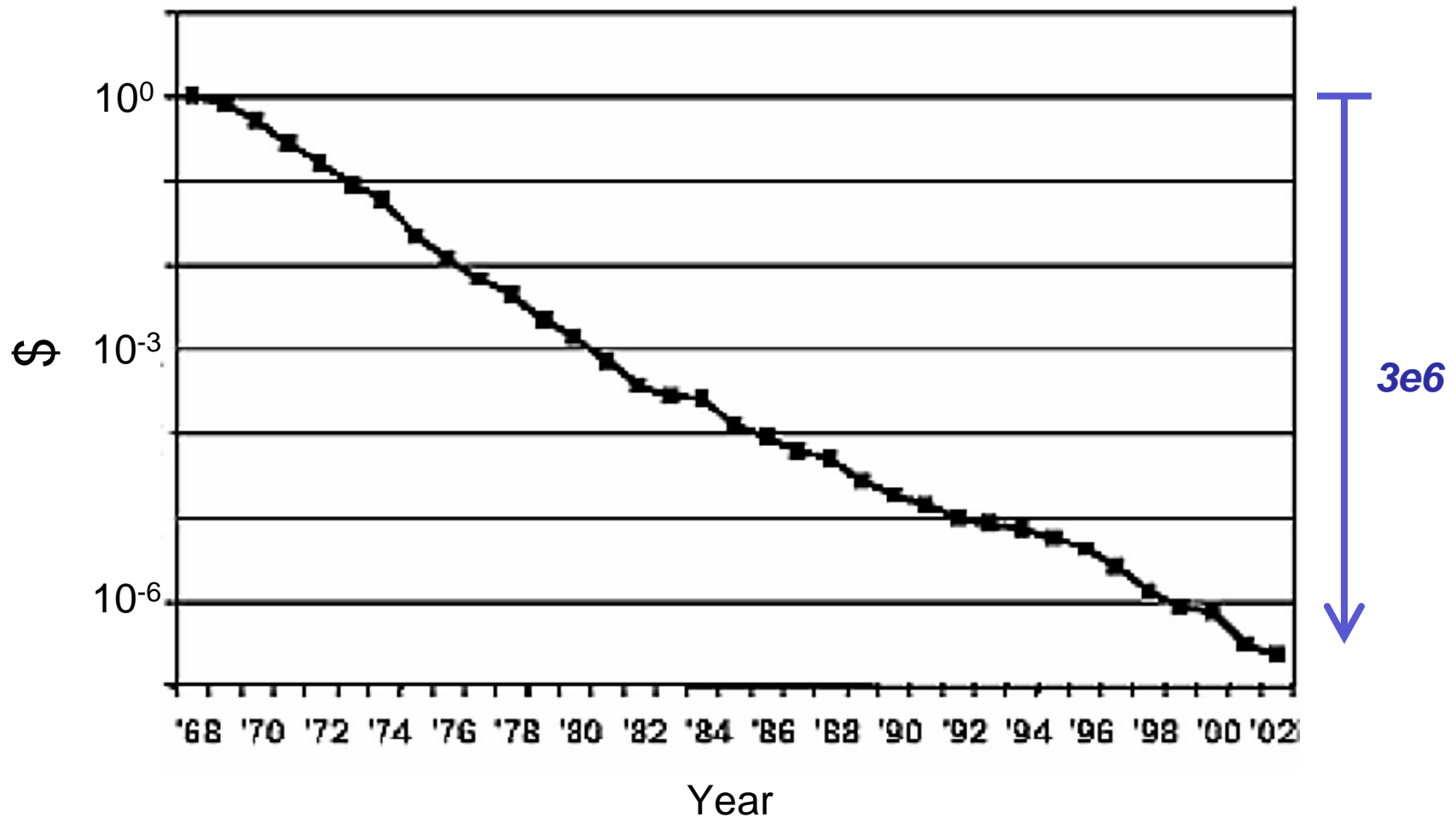




# CPU Clock Frequency

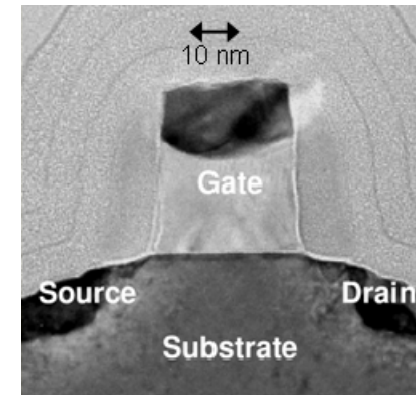


# Transistor Cost

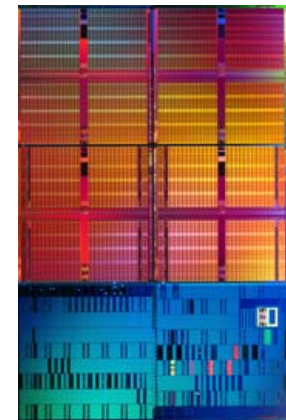


# Digital State of the Art

- 65 nm node:
  - SRAM test chip Nov. 2003
  - production Nov. 2005
  - “crossover” 3Q 2006



- 45 nm node:
  - 153MB SRAM Jan. 2006
  - $>10^9$  MOSFETs
  - production 3Q '07



# Failures of Classical Scaling

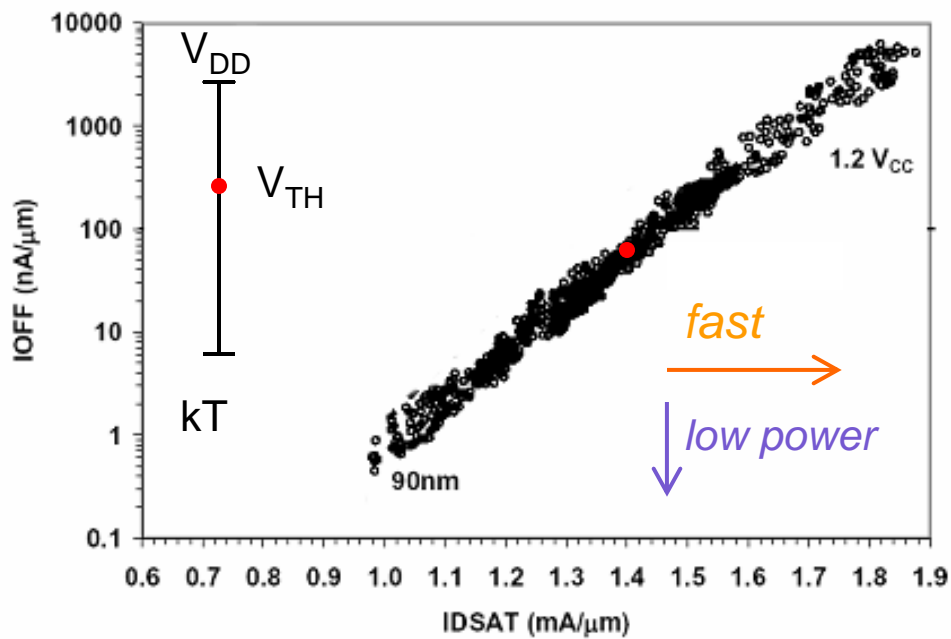
- ignores  $kT$
- ignores mobility degradation and velocity saturation
- ignores fringing capacitance
- ignores tunneling
- ignores atomistic effects
- ignores industry economics

# $kT \neq 0$

- MOSFET in weak inversion when  $V_{gs} < V_{th}$ :

$$I_D = I_0 e^{\frac{q(V_{GS} - V_{TH})}{nkT}} \Rightarrow I_{off} = I_0 e^{\frac{-qV_{TH}}{nkT}}$$

- Can't continue to scale  $V_{TH}$
- Tradeoff of speed for leakage current (static power)
- Multi- $V_{TH}$  processes

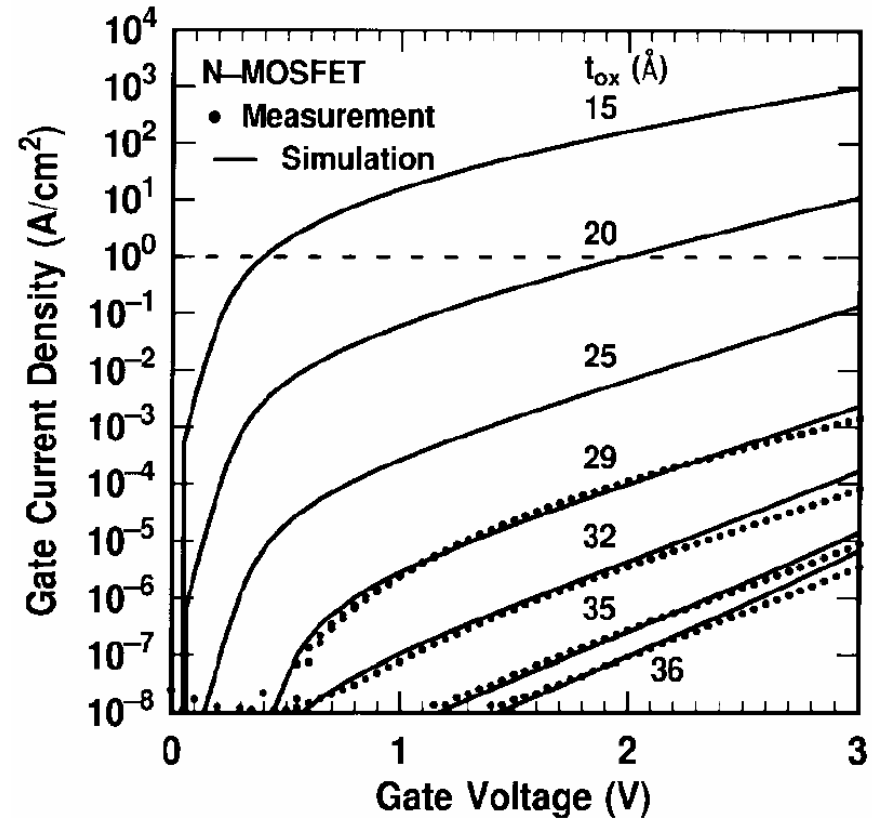


# Gate tunneling current

- Significant tunneling through SiO<sub>2</sub> when t<sub>ox</sub> < 3nm
- J<sub>tunnel</sub> increases 100X per generation
- Replace SiO<sub>2</sub> with high-κ dielectric (?)

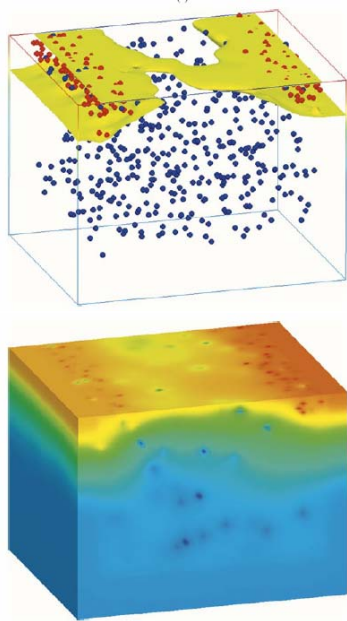
$$EOT = t_{hi-\kappa} \frac{\epsilon_{SiO_2}}{\epsilon_{hi-\kappa}}$$

- Multi-t<sub>ox</sub> processes



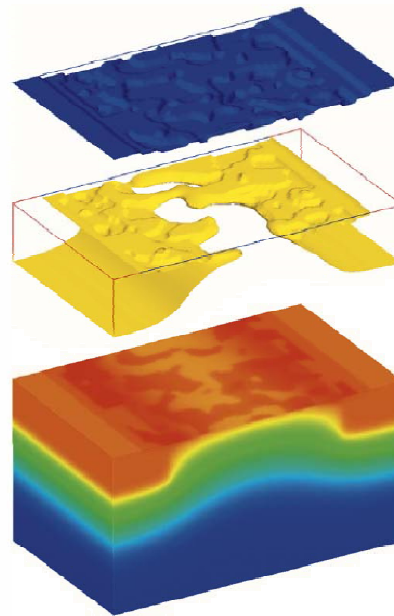
# Atomistic Effects

random dopant distribution



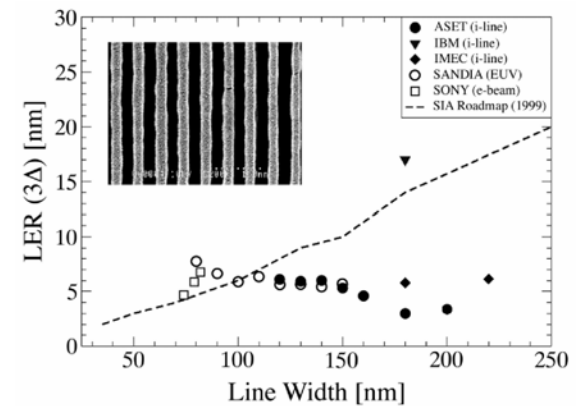
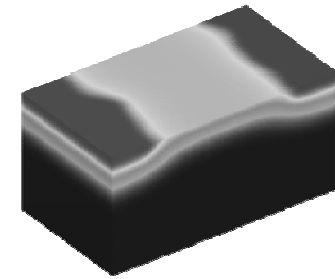
$\sigma V_{TH}$ , RTS

oxide thickness variation



$\sigma V_{TH}$ ,  $\sigma J_{tunnel}$ ,  $\sigma \mu$

line edge roughness

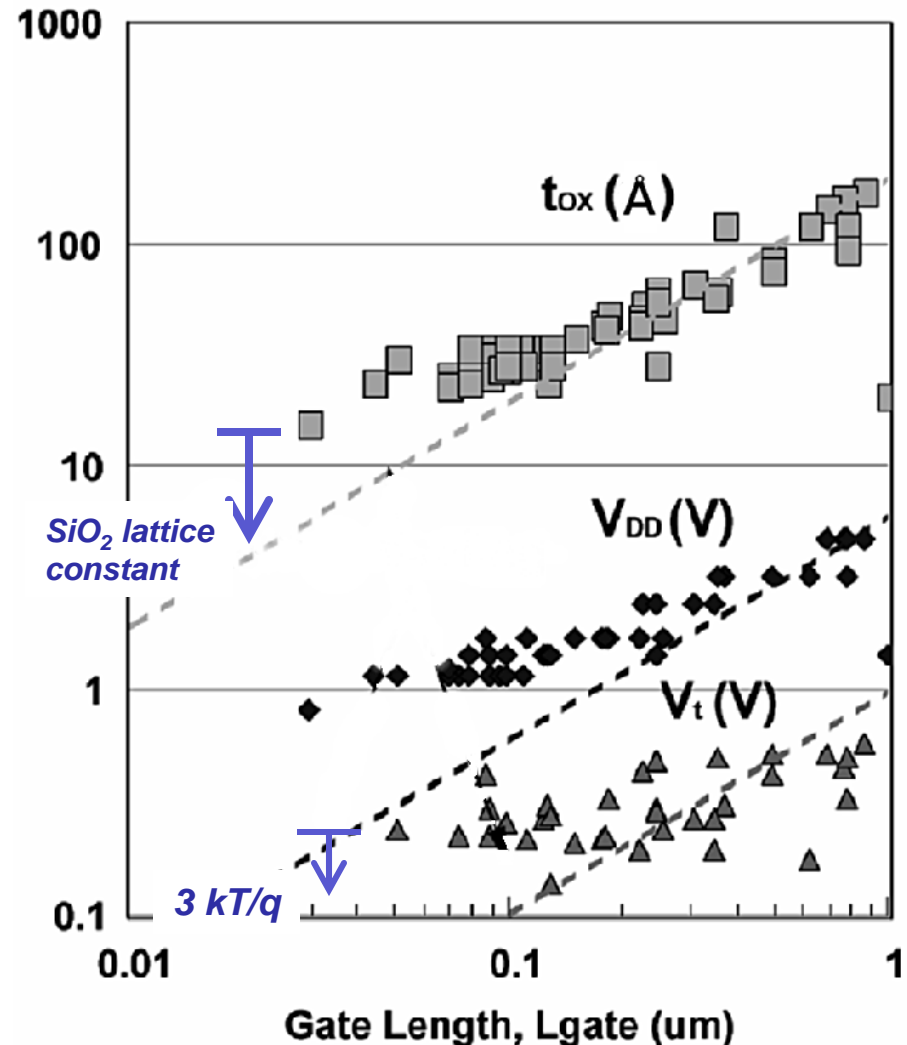


$\sigma V_{TH}$

A. Asenov, IEEE Trans. Electron Dev. 50(9), 1837 (2003)

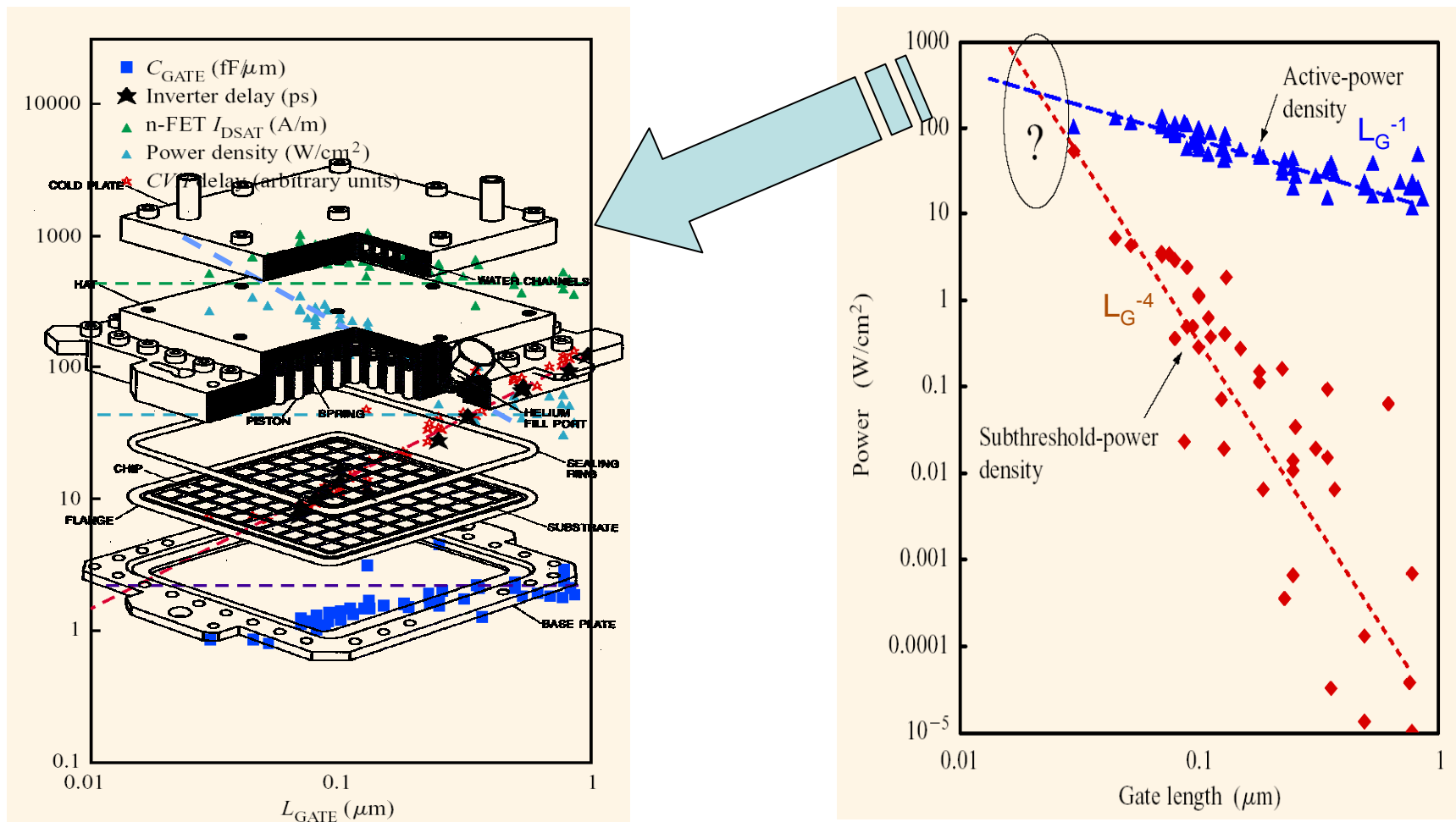
# Scaling in Practice

- Until 180nm node:
  - follow classical scaling with  $\alpha = \sqrt{2}$
  - *2.8X performance per generation*
- Now:
  - continue (super) scaling  $L_g$
  - sub-scaling of  $t_{ox}$
  - $V_{DD}$ ,  $V_{TH}$  have stopped scaling
- Gate density and speed continue to scale
- Increase of E, conductance
- Switching energy decreases only by  $1/\alpha$  not  $1/\alpha^3$
- Power density *increase*  $\sim \alpha$
- *Static power* from leakage, gate tunneling make power problem worse





# Power is biggest impediment to further scaling

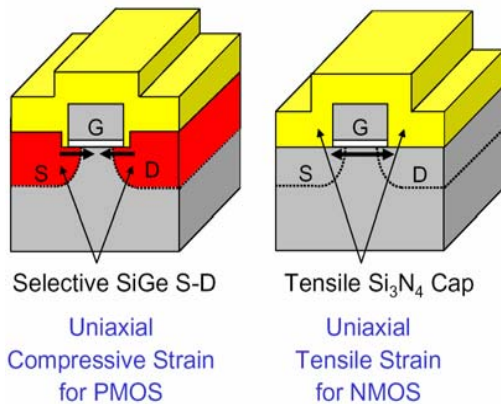


E. Nowak, IBM J. Res. & Dev. 45(2), 169 (2002)

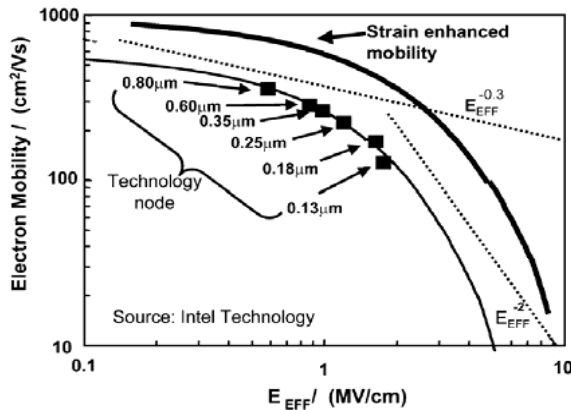
# Next-generation Transistors

## Strain Engineering

- Reduce mobility degradation



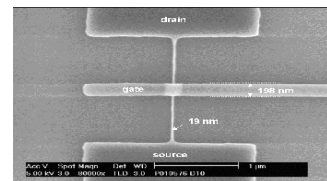
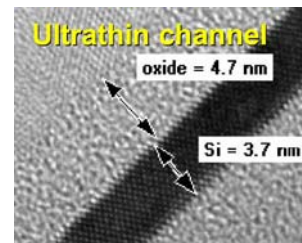
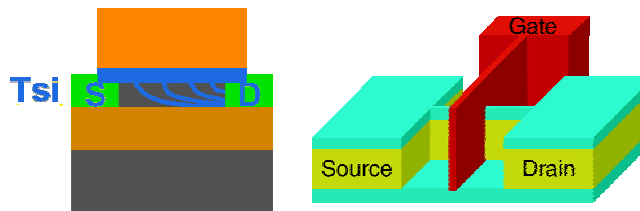
M. Bohr, Intel, 2003 IEDM



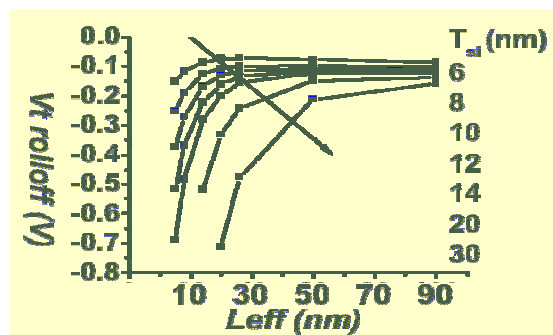
S. Thompson, Intel, IEEE T-ED 51(11), 1790 (2004)

## UTSOI, DG-FET

- Suppress SCE through improved electrostatics



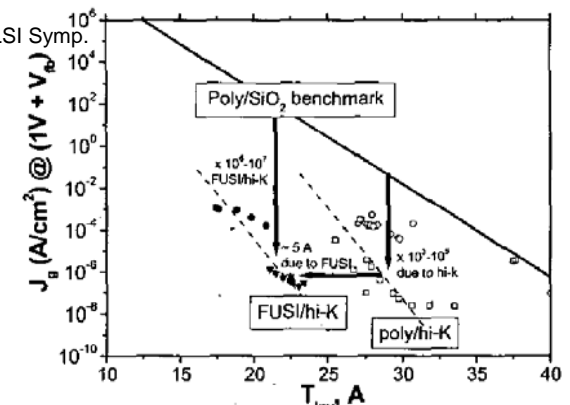
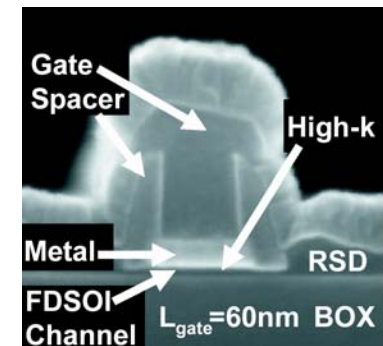
F.-L. Yang et al., IMEC, 200 VLSI Symp.



M. leong, IBM, Sol. State and IC Tech. 2004

## High-k gate dielectric

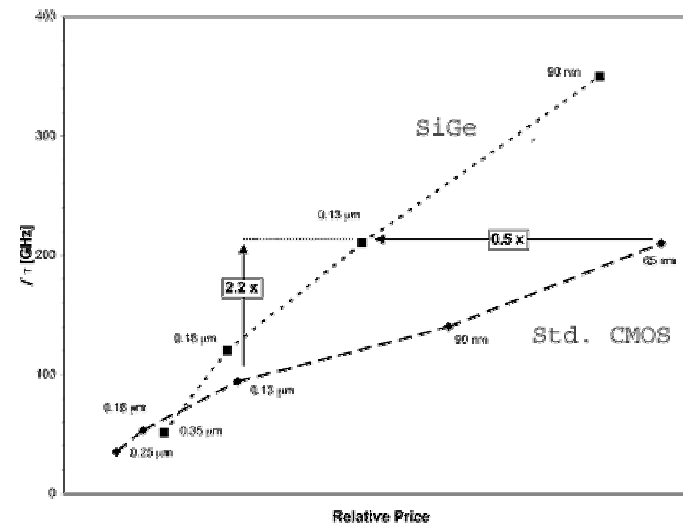
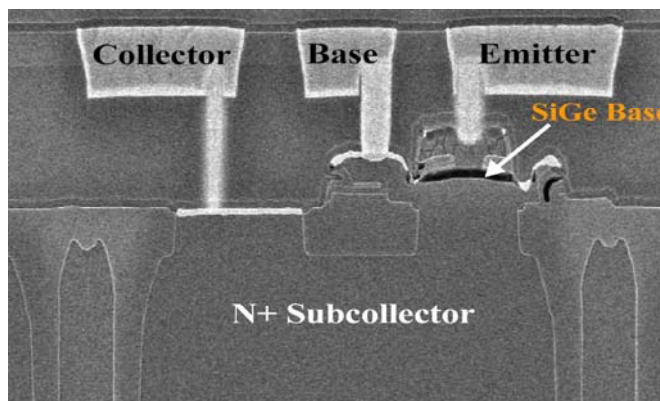
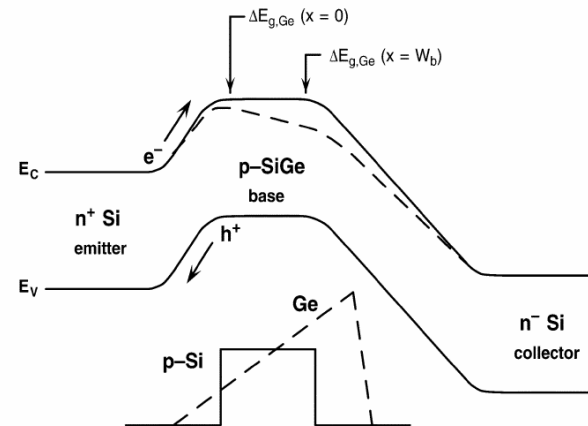
- Suppress  $J_{tunnel}$



E. Gusev et al., IBM, 2004 IEDM

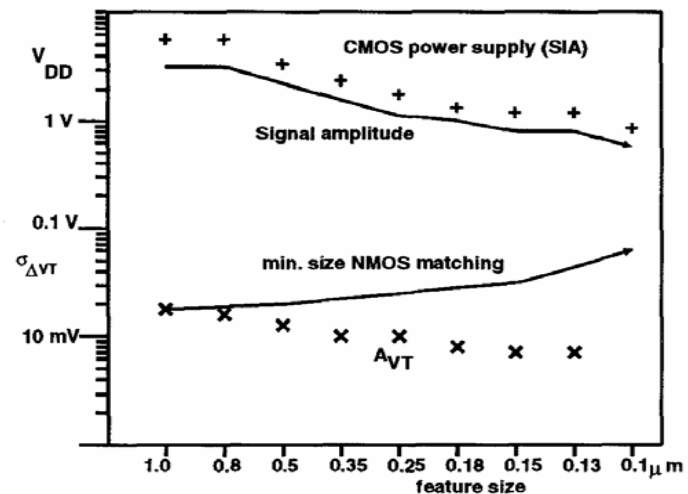
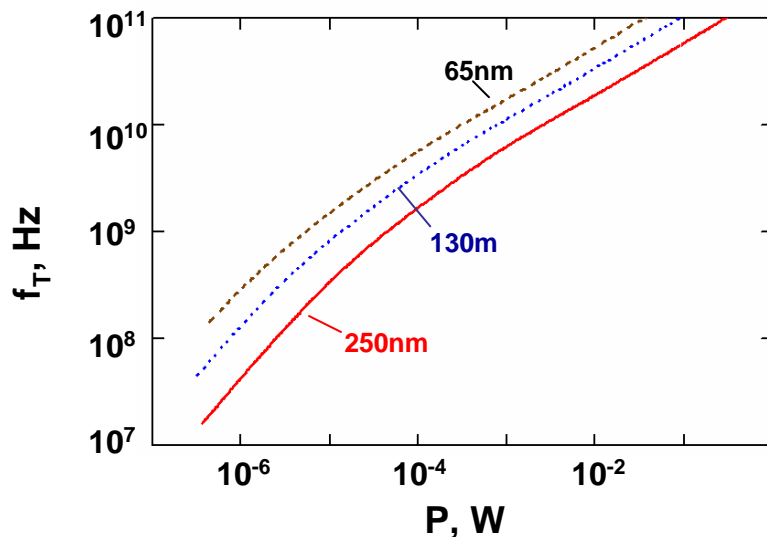
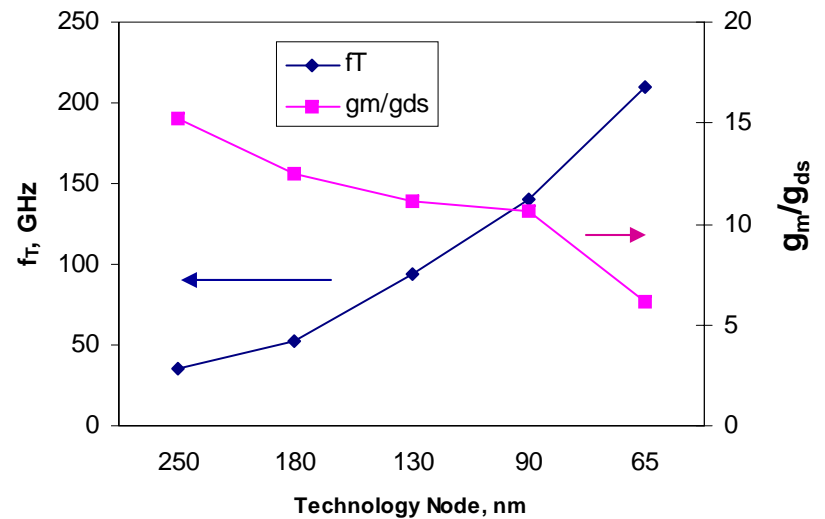
# SiGe Heterojunction Bipolar Transistor (HBT)

- Power-performance ~ 2X standard CMOS at same feature size
- Cost also ~ 2X
- Provides 3 – 4 year “head start” over CMOS
- Eventually CMOS provides better cost-performance



# Analog: Speed, Gain & Matching

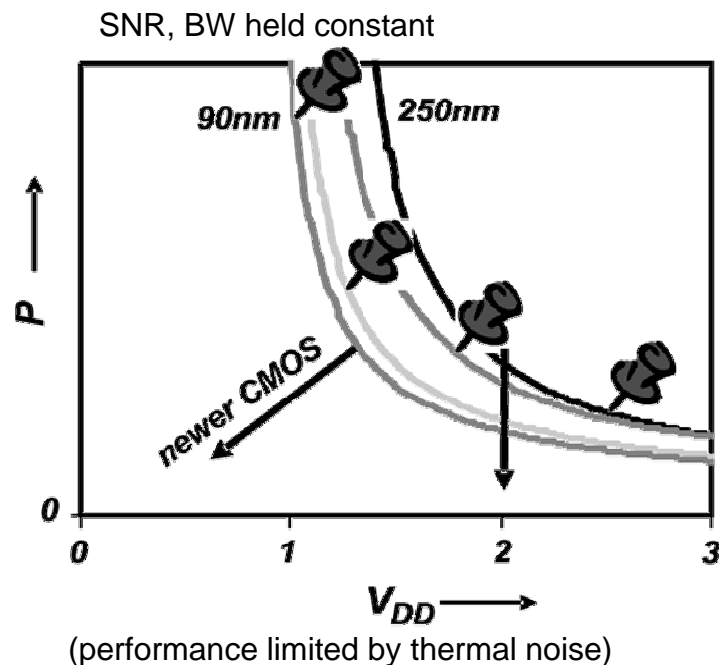
- Speed/intrinsic gain tradeoff
  - $f_T \sim 1/L_G$  for min- $L_G$  devices
  - Output conductance  $g_{ds}$  sensitive to geometry and bias
  - Gain  $g_m/g_{ds}$  severely degraded in ultra-scaled devices:
    - failure to adhere to classical constant-E scaling
- Threshold Mismatch
  - Dopant fluctuations:  $\sigma_{\Delta V_{TH}, LG-\min} \sim \alpha$
  - Overcome by increasing  $W^*L$
  - Power penalty



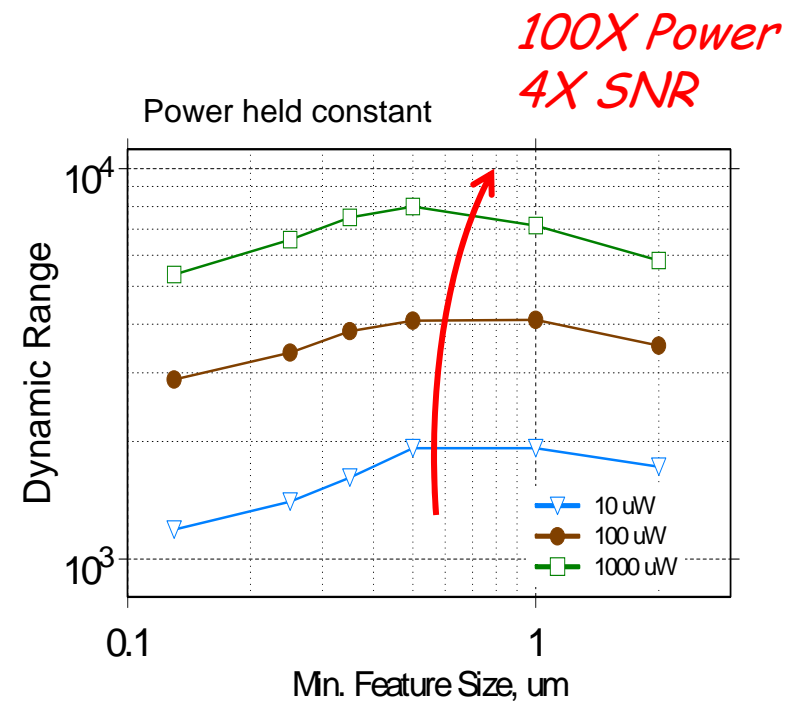
Pelgrom, Philips, 1998 IEDM

# Analog Low- $V_{DD}$ Challenges

- Increasing ratio of  $V_{TH}/V_{DD}$  rules out use of many classical analog design topologies, e.g. cascodes.
- To achieve same performance at lower  $V_{DD}$ , analog circuits need increased power.

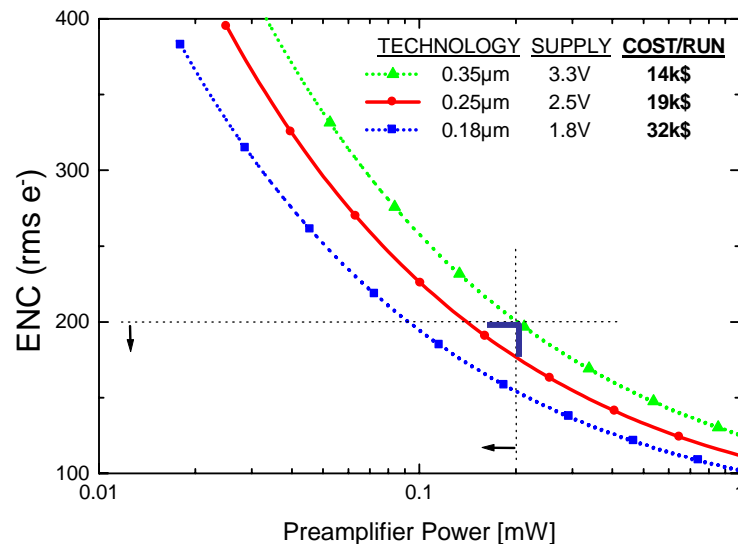


A. Annema et al., IEEE JSSS 40(1), 132 (2005)

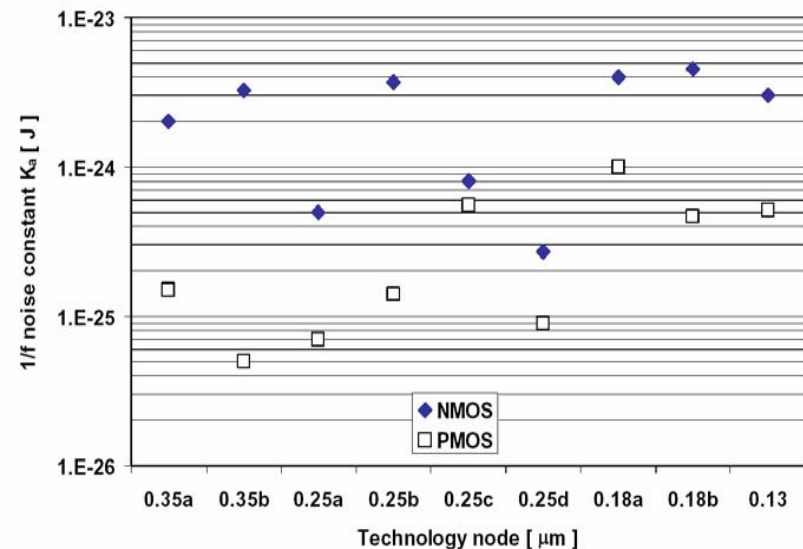


# Noise in scaled CMOS

- For CSA, consider noise in relation to gate capacitance
- Thermal noise improvement from higher  $f_T$ :
  - $ENC_{th} \sim \sqrt{1/\alpha}$
- 1/f noise depends on interface trap density, device area, inversion charge density –
  - no consistent trend with scaling
- Choice of L,W for minimum noise needs to account for moderate inversion operation
- Gate leakage current shot noise (parallel)



P O'Connor and G. De Geronimo, Prospects for charge sensitive amplifiers in scaled CMOS, NIM A480, 713 (Mar. 2002)

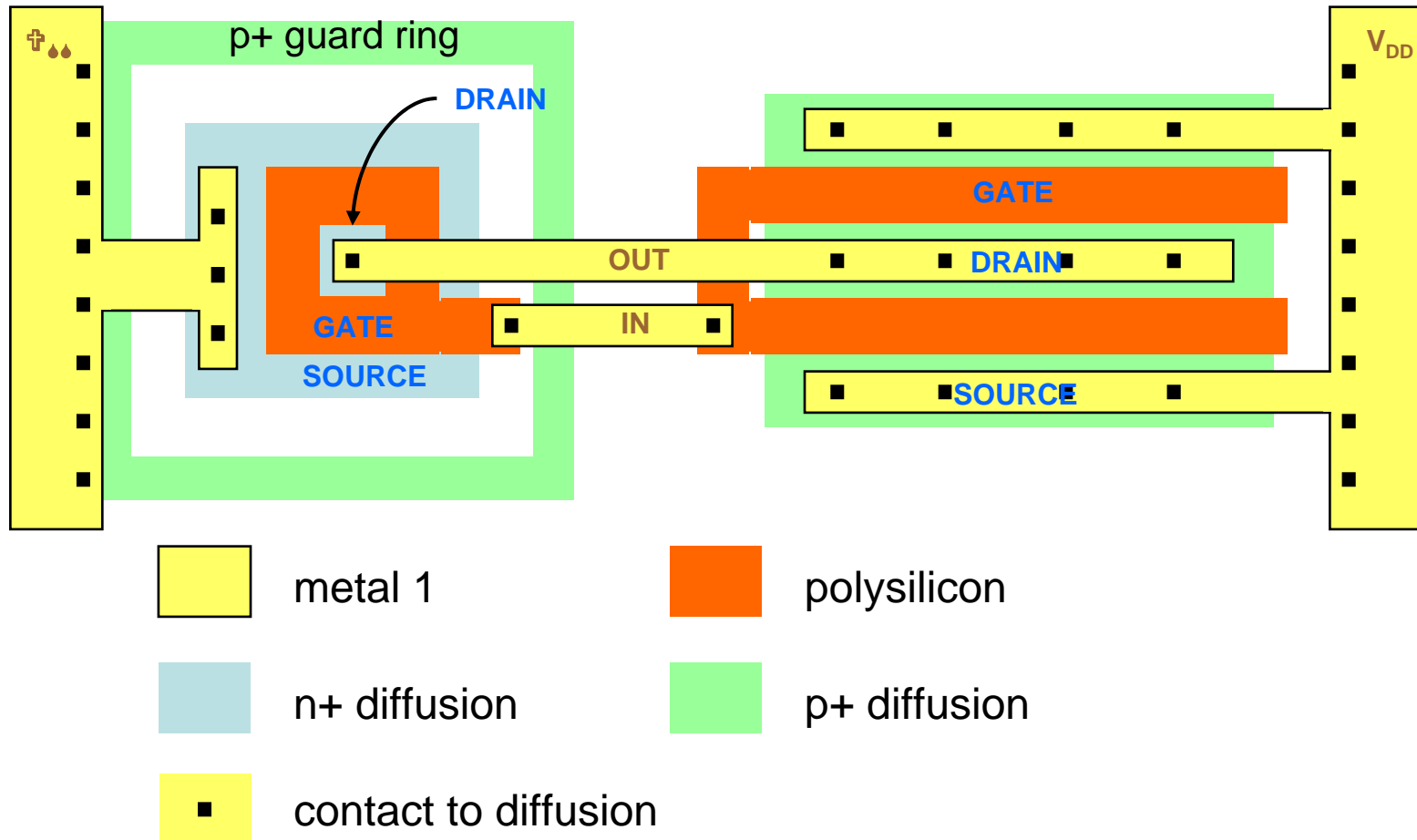


G. Anelli 2005

# Radiation Tolerant Inverter

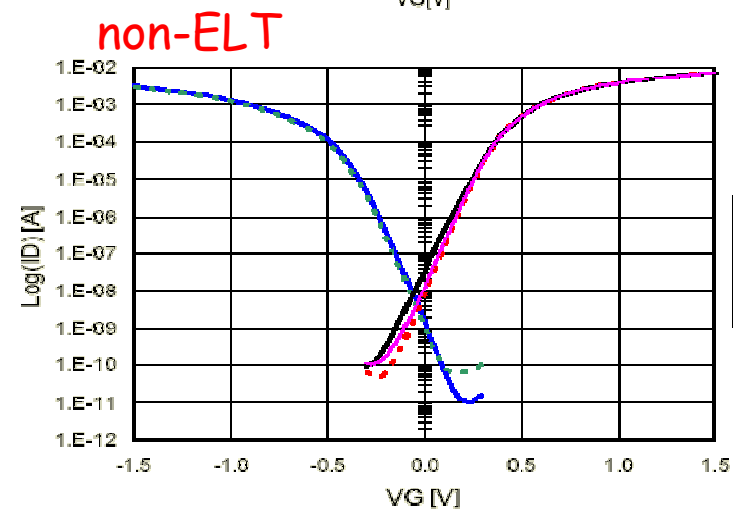
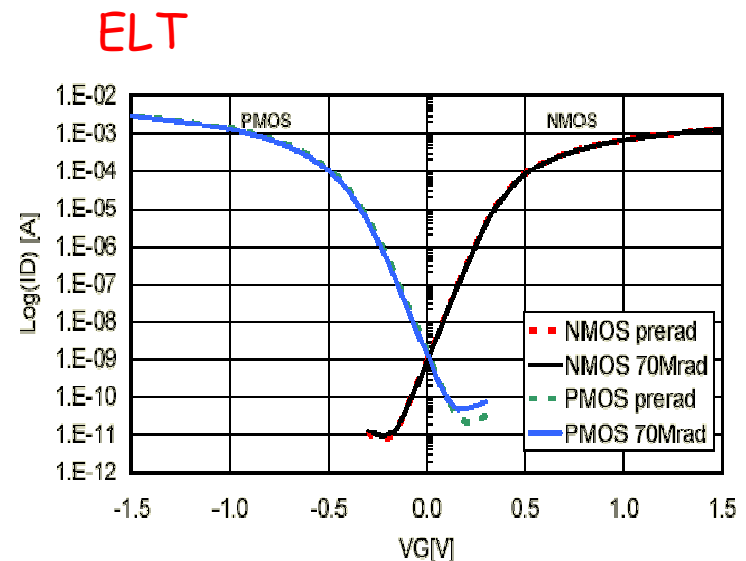
NMOS Enclosed Layout Transistor (ELT)

PMOS



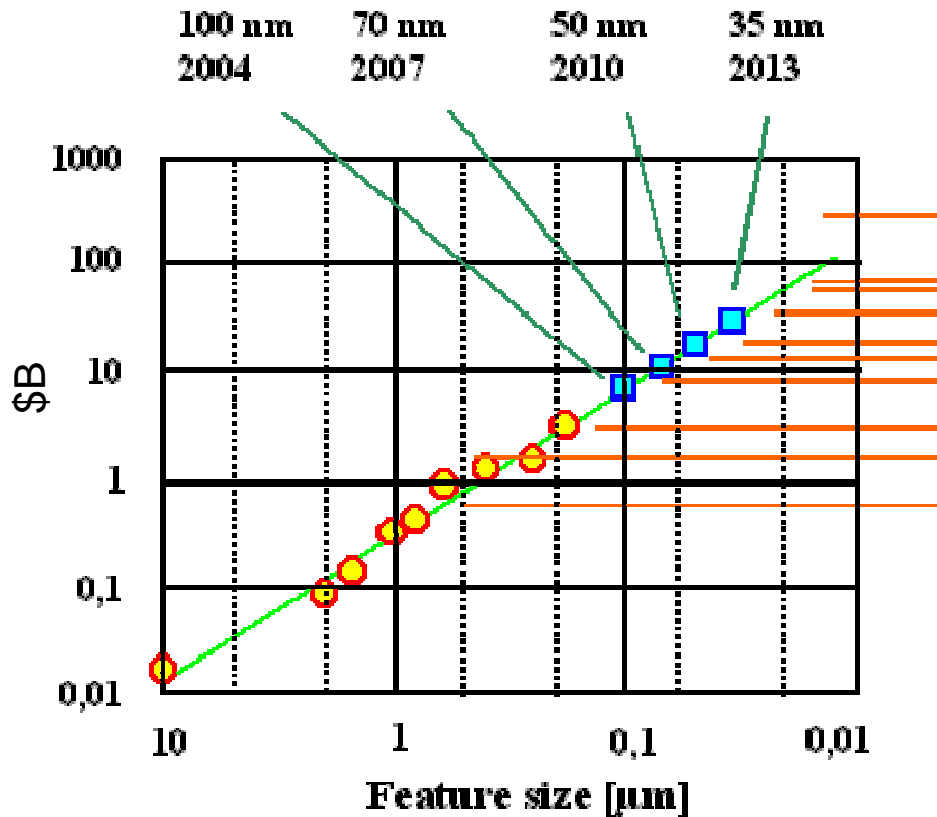
# Radiation Effects below $0.25\mu\text{m}$

- Thinner gate oxides  $\rightarrow$  more tolerance to Total Ionizing Dose
- Thick field oxide charging  $\rightarrow$ 
  - edge leakage in NMOS
  - loss of isolation NWELL-NWELL
- $0.13\mu\text{m}$  IBM technology harder than  $0.25\mu\text{m}$ :
  - non-ELT devices OK except narrow/thick-oxide NMOS
  - to 70 Mrad+
  - lateral isolation OK, no guard ring needed
  - SEU cross section higher, lower critical charge
  - No radiation-induced SEL





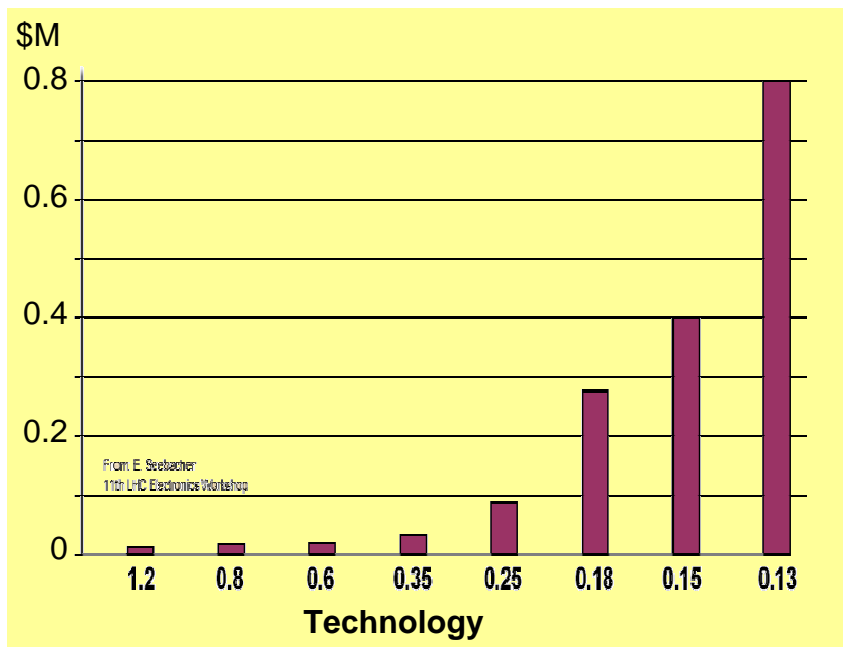
# Fab Line Cost



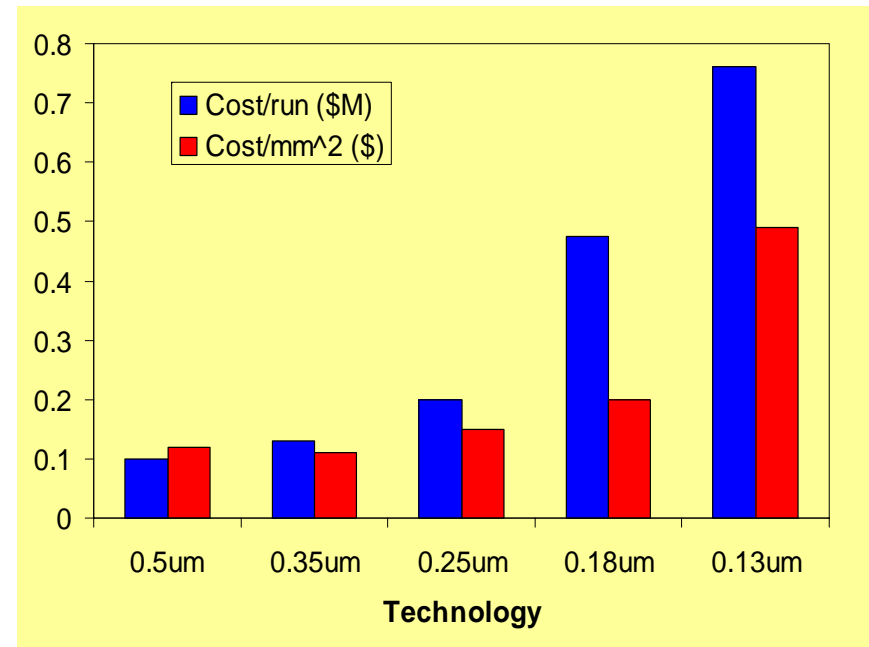
[http://www.tf.uni-kiel.de/matwis/amat/elmat\\_en/index.html](http://www.tf.uni-kiel.de/matwis/amat/elmat_en/index.html)  
 Electronic Materials  
 © Prof. Dr. Helmut Föll  
 University of Kiel; Faculty of Engineering

# Mask Set and Fabrication Cost

## MASK SET



## ENGINEERING RUN



# Example - BNL ASIC Design Group

- Develops Low Noise FEE for gas and semiconductor detectors
  - accelerator experiments
  - medical imaging
  - astrophysics
  - homeland security
- 70% Federal, 30% commercial
- Staff
  - 5 ASIC professionals
  - 1 DAQ engineer
  - 1 Technician
- CAD suite and test labs
- 7 – 8 runs/year through MOSIS
  - 0.35, 0.25, and 0.18um mixed-signal CMOS
  - 5K – 600K MOSFETs per chip
  - \$20K – \$80K per MPW run
- Development cost per design ~ *\$200K x no. revisions needed*

# Summary

- Power dissipation is the major obstacle to further CMOS scaling.
- Foundry and mask costs going up as process options (multi- $V_{th}$ , multi- $t_{ox}$ , HBT, passives, etc.) added for SOC.
- Analog design is compromised by the low supply rail.
- Except for high radiation resistance and packing density, ultra-scaled technologies offer few advantages to justify their enormous cost.
- Plenty of opportunity to innovate in (n-4)-generation CMOS.

# Bon Appétit!

